

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office JUL 12 2005 SCE	Attorney's Docket No. 12732-061002	Application No. 10/792,132
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Taketomi Asami et al.	
		Filing Date March 4, 2004	Group Art Unit

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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Examiner Signature JOSEPH NGUYEN	Date Considered 11/09/05
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass
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